

Amendments to the Specification

Please amend the paragraph beginning on page 2, line 24 as follows:

FIG. 13 is an oblique view schematically illustrating a conventional method for measuring beam blur; FIG. 14 depicts certain details of the method in schematic block form; and FIG. 15 is a plot of exemplary measurement results obtained using the method. This method for measuring beam blur is disclosed, for example, in Japan *Kôkai* Patent Document No.

Hei 10-289851 (corresponding to U.S. Patent No. 6,059,981) and in Japan Patent Application No. 2000-12620 *Kôkai* Patent Document No. 2001-203149.